



LIST OF RELATED CASES

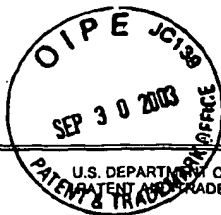
	<u>Docket Number</u>	<u>Serial or Patent Number</u>	<u>Filing or Issue Date</u>	<u>Inventor/ Applicant</u>
HR	239736US2*	10/608,155	06/30/03	MATSUSHITA
HR	254384US2	10/865,927	06/14/04	MATSUSHITA et al.

Shelley Ross 10/19/2005

*Present Application; listed for information

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Form PTO 1449 (Modified)		U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE		ATTY DOCKET NO. 239736US2		SERIAL NO. 10/608,155	
LIST OF REFERENCES CITED BY APPLICANT				APPLICANT Hiroshi MATSUSHITA		GROUP 2133 2826	
				FILING DATE June 30, 2003			
U.S. PATENT DOCUMENTS							
EXAMINER INITIAL		DOCUMENT NUMBER	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	AA						
	AB						
	AC						
	AD						
	AE						
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FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	TRANSLATION YES NO		
	AO						
	AP						
	AQ						
	AR						
	AS						
	AT						
	AU						
	AV						
OTHER REFERENCES (Including Author, Title, Date, Pertinent Pages, etc.)							
HR	AW	H. MATSUSHITA, et al., IEEE Transactions on Semiconductor Manufacturing, vol. 15, no. 4, pages 1-7, "HIGHLY SENSITIVE INSPECTION SYSTEM FOR LITHOGRAPHY-RELATED FAULTS IN AGILE-FAB - DETECTING ALGORITHM FOR MONITORING AND EVALUATION OF YIELD IMPACT", November 2002					
HR	AX	K. MITSUTAKE, et al., Proc. 10th Int. Symp. Semiconductor Manufacturing, pages 247-250, "NEW METHOD OF EXTRACTION OF SYSTEMATIC FAILURE COMPONENT", 2001					
HR	AY	M. SUGIMOTO, et al., Proc. 10th Int. Symp. Semiconductor Manufacturing, pages 275-278, "CHARACTERIZATION ALGORITHM OF FAILURE DISTRIBUTION FOR LSI YIELD IMPROVEMENT", 2001					
HR	AZ	K. NAKAMAE, et al., Proc. 4 th Int. Conf. Modeling and Simulation of Microsystems, pages 598-601, "FAIL PATTERN CLASSIFICATION AND ANALYSIS SYSTEM OF MEMORY FAIL BIT MAPS", 2001					<input type="checkbox"/> Additional References sheet(s) attached
Examiner <i>Chen Robeshole</i>					Date Considered 10/19/2005		
*Examiner: Initial if reference is considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.							